



C O N T E N T S

MICRONANO

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New Year's Greetings

As we welcome in 2010, it gives me great pleasure to wish you all a happy New Year and to offer some thoughts on this new beginning. First, I would like to express my gratitude to all who have given their cooperation and support to the Micromachine Center and the BEANS Laboratory.

Last year I was appointed chairman of both entities at the joint board meeting held on September 17 and assumed my duties on the following day. While I am deeply honored to receive such an important responsibility, at the same time I fully realize the magnitude of these duties. As chairman I will strive to continue our efforts in developing micromachines, MEMS, and other micro/nano fields, and I shall be grateful for your support.

Forgive me for starting out the New Year on a somber note, but as you know the state of Japan's economy remains dire due in part to the failure of Lehman Bros. the year before last and the Dubai debt crisis this past fall. In order to break out of this situation, it is essential that we intensify our efforts in technological development, which is the key to keeping Japan's industries internationally competitive. For this reason, we must double our efforts in technological development related to MEMS and other micro/nano fields, now considered important industrial technologies.

To do this, the BEANS Project to develop next-generation device manufacturing technologies that fuse different fields, which was established to develop core process technologies required for creating innovative next-generation devices and to build a platform for this development, has set its sights on developing applications in a wide range of fields that include energy and the environment, safety and security, and health and medical care, as well as in traditional fields of application. We hope to increase and expand the market for micro/nano devices by creating new devices to support Japan's industry across diverse fields.

The BEANS Project is now entering its third year, which is the interim evaluation year. In 2010, the achievements of the project will become more evident and will help us establish a roadmap for developing base technologies required to produce innovative next-generation devices. Therefore, I would like to thank you all in advance for your continued support and cooperation with regard to the activities of the BEANS Laboratory.

On another note, the Micromachine Center has entered its 18th year this January. However, after the three laws on reforming the public interest corporations system went into effect in December 2008, the Micromachine Center decided to shift from its current public interest status to a general incorporated foundation in order to maintain a level of freedom amid the rapidly fluctuating social environment and ensure a stable environment for conducting operations. Accordingly, we have submitted an application to the Cabinet Office for making this change. In the event that our application is approved, we will reevaluate our roles and responsibilities as a general incorporated foundation and will continue our activities in the hope of contributing to Japan's international competitiveness in industry and to the creation of a future affluent society.

In regard to the activities of the MEMS Industry Forum under the Micromachine Center, this year we will continue working with all those involved in studies aimed at strengthening an infrastructure for the future creation of nanotechnology R&D centers. We ask for your continued support and cooperation in this matter as well.

Finally, on behalf of the Micromachine Center and the BEANS Laboratory, I would like to offer you all my sincerest wishes for a fruitful year. Thank you and Happy New Year.



**Hisao Sakuta,
Chairman**

Micromachine Center
BEANS Laboratory

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